

Title (en)

METHOD FOR IDENTIFYING SUBSTRATES WHICH ARE FAULTY OR HAVE BEEN INCORRECTLY INSERTED INTO A CVD REACTOR

Title (de)

VERFAHREN ZUM ERKENNEN FEHLERHAFTER ODER FEHLERHAFT IN EINEN CVD-REAKTOR EINGESETZTE SUBSTRATE

Title (fr)

PROCÉDÉ D'IDENTIFICATION DE SUBSTRATS DÉFECTUEUX OU INCORRECTEMENT INSÉRÉS DANS UN RÉACTEUR DE DÉPÔT CHIMIQUE EN PHASE VAPEUR

Publication

**EP 4189136 A1 20230607 (DE)**

Application

**EP 21746480 A 20210720**

Priority

- DE 102020119873 A 20200728
- EP 2021070262 W 20210720

Abstract (en)

[origin: WO2022023122A1] The invention relates to a method for identifying substrates (3) which are faulty or have been incorrectly inserted in a CVD reactor, with the aid of one or more optical sensors (3), which sense properties of the surfaces of the substrates, for example layer thickness or temperature, before or during a treatment process of the substrates (3) within the CVD reactor housing (1). The measurement values provided by the sensors (3) can be plotted in the form of a measurement curve, and patterns are obtained from the measurement curve, each pattern corresponding to one of the substrates (3). The patterns are compared with each other or with a mean (Lm) calculated from the patterns.

IPC 8 full level

**C23C 16/458** (2006.01); **C23C 16/46** (2006.01); **C23C 16/52** (2006.01); **G01J 5/00** (2022.01); **H01L 21/66** (2006.01); **H01L 21/67** (2006.01); **H01L 21/687** (2006.01)

CPC (source: EP KR US)

**C23C 16/4584** (2013.01 - EP KR US); **C23C 16/4586** (2013.01 - EP KR); **C23C 16/46** (2013.01 - EP KR US); **C23C 16/52** (2013.01 - EP KR US); **G06T 7/004** (2013.01 - KR); **H01L 21/67103** (2013.01 - EP KR); **H01L 21/67248** (2013.01 - EP KR); **H01L 21/67253** (2013.01 - EP KR); **H01L 21/67288** (2013.01 - EP KR); **H01L 21/68764** (2013.01 - EP); **H01L 21/68771** (2013.01 - EP KR); **H01L 22/12** (2013.01 - EP KR); **G06T 2207/30148** (2013.01 - KR)

Citation (search report)

See references of WO 2022023122A1

Designated contracting state (EPC)

AL AT BE BG CH CY CZ DE DK EE ES FI FR GB GR HR HU IE IS IT LI LT LU LV MC MK MT NL NO PL PT RO RS SE SI SK SM TR

Designated extension state (EPC)

BA ME

Designated validation state (EPC)

KH MA MD TN

DOCDB simple family (publication)

**DE 102020119873 A1 20220203**; CN 116034184 A 20230428; EP 4189136 A1 20230607; JP 2023535209 A 20230816; KR 20230048078 A 20230410; TW 202221162 A 20220601; US 2023295807 A1 20230921; WO 2022023122 A1 20220203

DOCDB simple family (application)

**DE 102020119873 A 20200728**; CN 202180055095 A 20210720; EP 2021070262 W 20210720; EP 21746480 A 20210720; JP 2023504708 A 20210720; KR 20237006771 A 20210720; TW 110127267 A 20210726; US 202118018528 A 20210720